



Attorney's Docket No.: 042390P8276

Patent

#9/4
10
11/26/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Anne E. Miller et al.
U.S. Serial No: 09/715,282
Filed: November 16, 2000
For: SLURRY AND METHOD FOR
CHEMICAL MECHANICAL POLISHING
OF COPPER

Examiner: Chen, Kin Chan
Art Unit: 1765

Assistant Commissioner for Patents
and Trademarks
Washington, D.C. 20231

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AMENDMENT AND RESPONSE

Dear Sir:

This is in response to the Office Action mailed August 12, 2002. Applicant respectfully requests the Examiner to enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Assistant Commissioner of Patents, Washington, D.C. 20231
on November 12, 2002 Date of Deposit

Teresa Edwards

Name of Person Mailing Correspondence

Teresa Edwards
Signature

November 12, 2002
Date